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- Sedky, Sherif  
Dokki, Criza (EG)
- Caymax, Matty  
3001 Leuven (BE)
- Baert, Christiaan  
3001 Heverlee (BE)

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(71) Applicant: **INTERUNIVERSITAIR  
MICRO-ELEKTRONICA CENTRUM VZW**  
3001 Heverlee (BE)

(74) Representative: **Van Malderen, Joelle et al**  
**Office Van Malderen,**  
**Place Reine Fabiola 6/1**  
**1083 Bruxelles (BE)**

(72) Inventors:  
• Fiorini, Paolo  
1180 Brussels (BE)

(54) **Method of fabrication of an infrared radiation detector and more particularly an infrared sensitive bolometer**

(57) A method of fabricating an infrared sensitive bolometer, comprising the steps of:

- forming a sacrificial layer (11, 12 or 43) on a substrate (10 or 41);
- patterning said sacrificial layer (11, 12 or 43);
- depositing or growing a layer (13 or 42) consisting essentially of polycrystalline SiGe on said sacrificial layer;
- depositing an infrared absorber (49) on said polycrystalline SiGe layer;
- removing the sacrificial layer (11, 12 or 43).

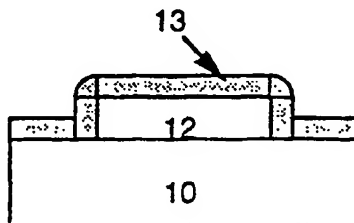


FIG. 1b

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# EUROPEAN SEARCH REPORT

Application Number  
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The present search report has been drawn up for all claims			
Place of search THE HAGUE		Date of completion of the search 24 August 1998	Examiner Visscher, E
CATEGORY OF CITED DOCUMENTS X : particularly relevant if taken alone Y : particularly relevant if combined with another document of the same category A : technological background O : non-written disclosure P : intermediate document		T : theory or principle underlying the invention E : earlier patent document, but published on, or after the filing date D : document cited in the application L : document cited for other reasons & : member of the same patent family, corresponding document	

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Application Number  
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A,D	US 5 367 167 A (KEENAN WILLIAM F) 22 November 1994 * abstract; figure 2 * * column 4, line 33 - column 5, line 24 *	15-20	
A,D	GERWEN VAN P ET AL: "THIN-FILM BORON-DOPED POLYCRYSTALLINE SILICON 70%-GERMANIUM 30% FOR THERMOPILES" SENSORS AND ACTUATORS A, vol. A53, no. 1/03, May 1996, pages 325-328, XP000620316 * abstract * * paragraph 3 *	1.9	
A	STEINER P ET AL: "MICROMACHINING APPLICATIONS OF POROUS SILICON" THIN SOLID FILMS, vol. 255, no. 1/02, 15 January 1995, pages 52-58, XP000607762 * abstract; figures 6,9 * * paragraph 3.2 *	1,7	
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DOCUMENTS CONSIDERED TO BE RELEVANT			
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			TECHNICAL FIELDS SEARCHED (Int.Cl.6)
The present search report has been drawn up for all claims			
Place of search <b>THE HAGUE</b>		Date of completion of the search <b>24 August 1998</b>	Examiner <b>Visscher, E</b>
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